



News Release

For Immediate Release

CyberOptics Semiconductor introduces WaferSense AGS200, designed to significantly improve film deposition, sputter and etch processing

WaferSense AGS200 improves thin film process uniformity while speeding semiconductor equipment set-up and maintenance.

BEAVERTON, OR - September 12, 2007 -- CyberOptics Semiconductor, a producer of precision products used for measuring critical parameters in semiconductor processes and equipment, and a subsidiary of CyberOptics Corp. (Nasdaq: CYBE), introduces its new 200mm WaferSense™ Auto Gapping System (AGS200). Designed for use in fabs manufacturing 200mm wafers, the wafer-like WaferSense AGS200 device wirelessly travels through deposition, sputtering and etch equipment to measure gaps between the shower heads and pedestal, reporting data in real time so that defects related to reduced tool productivity and yield loss can be quickly identified and remedied. The WaferSense AGS200 is accurate to ± 0.025 mm. It uses Bluetooth® technology to wirelessly send data to its application software for logging and analysis, and can operate for up to 4 hours between recharging.

Gaps between shower heads and wafers need to be precisely controlled for uniform film deposition / removal, and maximum wafer yield, making it necessary for fab engineers to continually monitor process equipment to ensure optimal alignment. Unlike current manual gap measurement methods that are time consuming, often inaccurate and waste hundreds of hours in engineers' time and lost equipment productivity, the wireless WaferSense AGS200 enables fab engineers to move the device directly into the process chambers while they are closed. Within minutes, gaps can be set and equipment settings checked - at process pressure/vacuum conditions - to speed setup and maintenance and improve tool yield.

"The 300mm Prime Initiative has underscored the necessity for improving tool productivity not only in highly automated fabs, but within all semiconductor fabs. It calls for new methods of analyzing data in order to improve process performance and reduce maintenance costs," said Craig Ramsey, General Manager of CyberOptics Semiconductor. "The WaferSense AGS200 allows fab engineers to achieve precise electrode gapping for greater process uniformity and higher yields, and to significantly reduce tool downtime resulting in higher productivity."

The patent-pending wireless WaferSense AGS200 uses contactless sensors to measure gaps at three places between shower heads and the pedestal. Because the AGS200 is wireless, there are no wires to break and no vacuum leaks. The system's GapView™ application software returns real-time gap measurements that can be displayed on a laptop or PC in numerical and graphic form. Each graphic is color-coded to make it easier to see when the gap is above, below or within the user defined target gap range, allowing fab engineers to analyze information and make adjustments quickly. The data can also be time-stamped and logged for documentation and later analysis. The display not only lets fab engineers set the right gap, but also lets them do machine matching to set the same gap across all tools for better tool-

to-tool process uniformity. Gap settings can be easily reproduced, speeding up setup, maintenance and troubleshooting, and equipment downtime is reduced to minutes instead of hours.

WaferSense AGS200 Key Specifications

- Form factor – Diameter 200 mm. Height 8.5 mm (0.295 inches). Weight 225 grams.
- Packaging – Anodized aluminum.
- Working distance – Measures gaps from 9 mm to 20 mm (0.35 inches to 0.79 inches).
- Gap accuracy – ± 0.025 mm (0.001 inches) with gaps of 9.5mm to 17.0 mm (0.37 inches 0.59 inches),
- Operating pressure - 760 to less than 10^{-6} Torr
- Battery operation – Operates for 4 hours between recharging.
- Bluetooth wireless communications – Uses the 2.4 GHz radio frequency band to communicate with WaferSense link that connects to host computer USB port.
- GapView™ application software – Displays numerical and graphical gap information. Each graphic is color-coded to make it easy to see whether it is above, below, or within the selected target gap range.
- Data logging – GapView can log time-stamped measurements to a CSV (comma separated values) file for documentation and/or analysis.
- Operating systems - For use with Windows® 2000, XP and Vista.

The WaferSense AGS200 product kit is available now and includes gapping wafer, clean box, USB communications link and GapView application software. A 300mm device is also available.

The Auto Gapping System joins the expanding family of WaferSense™ products that include: the Auto Teaching System (ATS) and the Auto Leveling System (ALS).

About CyberOptics Semiconductor:

CyberOptics Semiconductor designs and delivers precision products that measure critical parameters in semiconductor processes and equipment. Cyberoptics Semiconductor is a subsidiary of CyberOptics Corp. (Nasdaq: CYBE), one of the world's leading providers of process yield and throughput improvement solutions for electronic assembly and semiconductor capital equipment companies. For more information, visit the web site at: www.CyberopticsSemi.com, e-mail CSsales@cyberoptics.com, or call 800-366-9131.

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